

10/6/2,008

Refine Search

Search Results -

Terms	Documents
L1 and (oxygen adj atoms)	11

Database:

US Pre-Grant Publication Full-Text Database
US Patents Full-Text Database
US OCR Full-Text Database
EPO Abstracts Database
JPO Abstracts Database
Derwent World Patents Index
IBM Technical Disclosure Bulletins

Search:

L2

Refine Search

Recall Text

Clear

Interrupt

Search History

DATE: Sunday, March 07, 2004 [Printable Copy](#) [Create Case](#)

Set
Name Query
side by
side

Hit
Count Set
Name
result set

DB=USPT; PLUR=YES; OP=ADJ

L2 L1 and (oxygen adj atoms)

11 L2

L1 (silicon adj oxide) and (silicon adj nitride) and (antireflection near4
film)

156 L1

END OF SEARCH HISTORY

Hit List

Search Results - Record(s) 1 through 10 of 11 returned.

☐ 1. Document ID: US 6607986 B2

L2: Entry 1 of 11

File: USPT

Aug 19, 2003

US-PAT-NO: 6607986

DOCUMENT-IDENTIFIER: US 6607986 B2

**** See image for Certificate of Correction ****

TITLE: Dry etching method and semiconductor device manufacturing method

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw De
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	-----	---------

☐ 2. Document ID: US 6417083 B1

L2: Entry 2 of 11

File: USPT

Jul 9, 2002

US-PAT-NO: 6417083

DOCUMENT-IDENTIFIER: US 6417083 B1

TITLE: Methods for manufacturing semiconductor devices

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw De
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	-----	---------

☐ 3. Document ID: US 6350397 B1

L2: Entry 3 of 11

File: USPT

Feb 26, 2002

US-PAT-NO: 6350397

DOCUMENT-IDENTIFIER: US 6350397 B1

TITLE: Optical member with layer having a coating geometry and composition that enhance cleaning properties

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw De
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	-----	---------

☐ 4. Document ID: US 6297114 B1

L2: Entry 4 of 11

File: USPT

Oct 2, 2001

US-PAT-NO: 6297114

DOCUMENT-IDENTIFIER: US 6297114 B1

TITLE: Semiconductor device and process and apparatus of fabricating the same

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWIC	Draw. De
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	------	----------

☐ 5. Document ID: US 6270948 B1

L2: Entry 5 of 11

File: USPT

Aug 7, 2001

US-PAT-NO: 6270948

DOCUMENT-IDENTIFIER: US 6270948 B1

**** See image for Certificate of Correction ****

TITLE: Method of forming pattern

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWIC	Draw. De
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	------	----------

☐ 6. Document ID: US 5976684 A

L2: Entry 6 of 11

File: USPT

Nov 2, 1999

US-PAT-NO: 5976684

DOCUMENT-IDENTIFIER: US 5976684 A

TITLE: Organic substrate provided with a light absorptive antireflection film and process for its production

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWIC	Draw. De
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	------	----------

☐ 7. Document ID: US 5897377 A

L2: Entry 7 of 11

File: USPT

Apr 27, 1999

US-PAT-NO: 5897377

DOCUMENT-IDENTIFIER: US 5897377 A

TITLE: Semiconductor device manufacturing method with use of gas including acyl-group-containing compound

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWIC	Draw. De
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	------	----------

☐ 8. Document ID: US 5803975 A

L2: Entry 8 of 11

File: USPT

Sep 8, 1998

US-PAT-NO: 5803975

DOCUMENT-IDENTIFIER: US 5803975 A

**** See image for Certificate of Correction ****

TITLE: Microwave plasma processing apparatus and method therefor

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWC	Draw.D
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	-----	--------

☐ 9. Document ID: US 5730922 A

L2: Entry 9 of 11

File: USPT

Mar 24, 1998

US-PAT-NO: 5730922

DOCUMENT-IDENTIFIER: US 5730922 A

TITLE: Resin transfer molding process for composites

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWC	Draw.D
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	-----	--------

☐ 10. Document ID: US 5409777 A

L2: Entry 10 of 11

File: USPT

Apr 25, 1995

US-PAT-NO: 5409777

DOCUMENT-IDENTIFIER: US 5409777 A

**** See image for Certificate of Correction ****

TITLE: Laminates of polymer shaving perfluorocyclobutane rings

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWC	Draw.D
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	-----	--------

Clear	Generate Collection	Print	Fwd Refs	Bkwd Refs	Generate OACS
-------	---------------------	-------	----------	-----------	---------------

Terms	Documents
L1 and (oxygen adj atoms)	11

Display Format: TI

Change Format

[Previous Page](#)[Next Page](#)[Go to Doc#](#)

Hit List

Clear	Generate Collection	Print	Fwd Refs	Bkwd Refs
Generate OACS				

Search Results - Record(s) 11 through 11 of 11 returned.

☐ 11. Document ID: US 5246782 A

L2: Entry 11 of 11

File: USPT

Sep 21, 1993

US-PAT-NO: 5246782

DOCUMENT-IDENTIFIER: US 5246782 A

TITLE: Laminates of polymers having perfluorocyclobutane rings and polymers containing perfluorocyclobutane rings

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw. D
------	-------	----------	-------	--------	----------------	------	-----------	--	--	--------	-----	---------

Clear	Generate Collection	Print	Fwd Refs	Bkwd Refs	Generate OACS
-------	---------------------	-------	----------	-----------	---------------

Terms	Documents
L1 and (oxygen adj atoms)	11

Display Format:

[Previous Page](#)

[Next Page](#)

[Go to Doc#](#)